

STATUS AND PROSPECTS OF ELECTRON CYCLOTRON RESONANCE CHARGE BREEDER

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Outline

- Motivation
- Status of ECR CB operation
- Can ECR booster be improved?
- prospects for EURISOL RIB facility

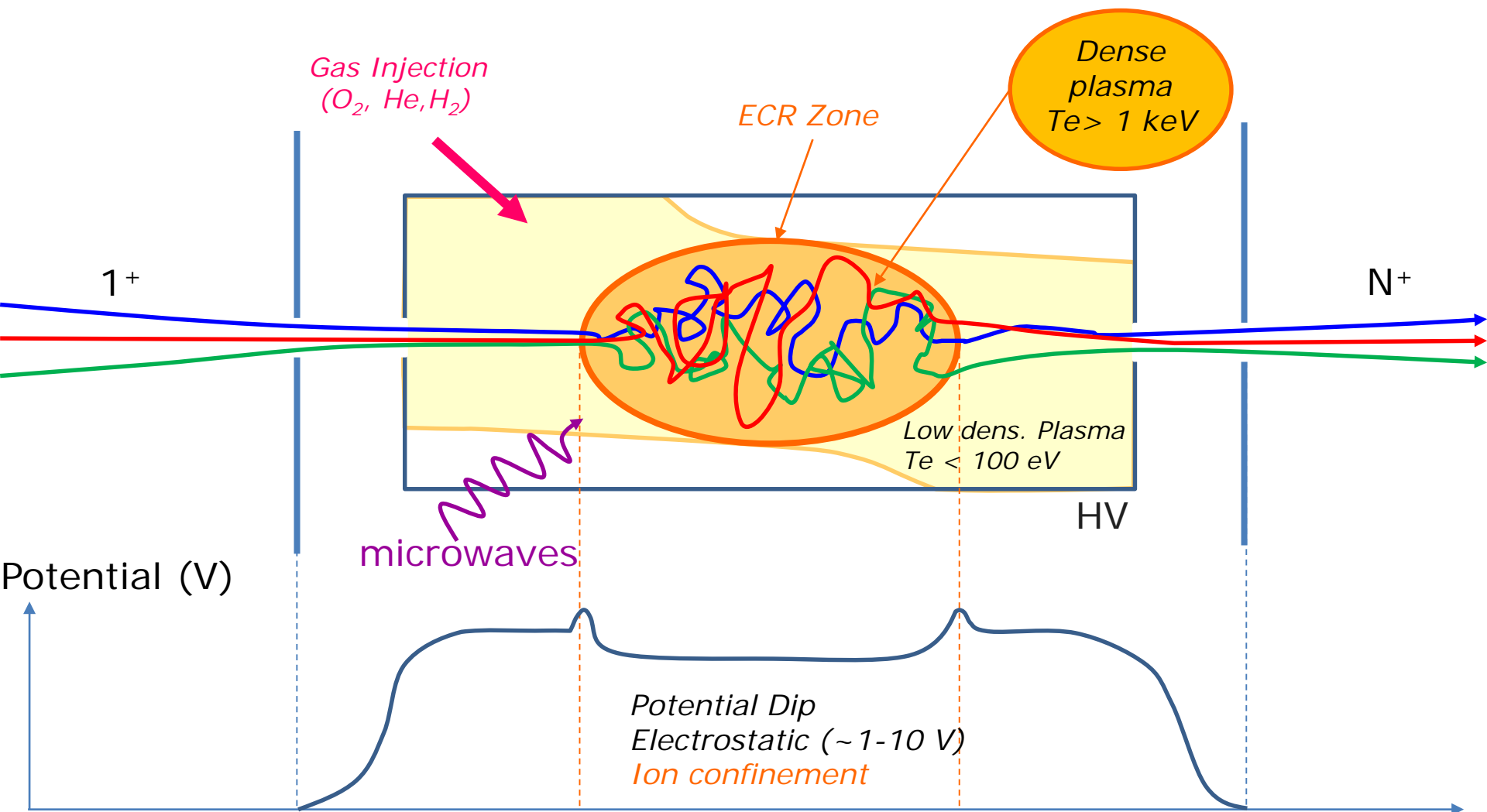


MOTIVATION

- Argonne stopped its ECR charge breeder and switched to an EBIS one
- TRIUMF is building an EBIS charge breeder to improve the RIB purity for experiments
 - Many RIB physicists have consequently concluded ECR boosters research is « dead » (« RIP » ECR CB!)
- Are ECR CB Really DEAD?
- Can they be upgraded?
- Is there a future to ECR charge breeders?
- Testing ideas with you

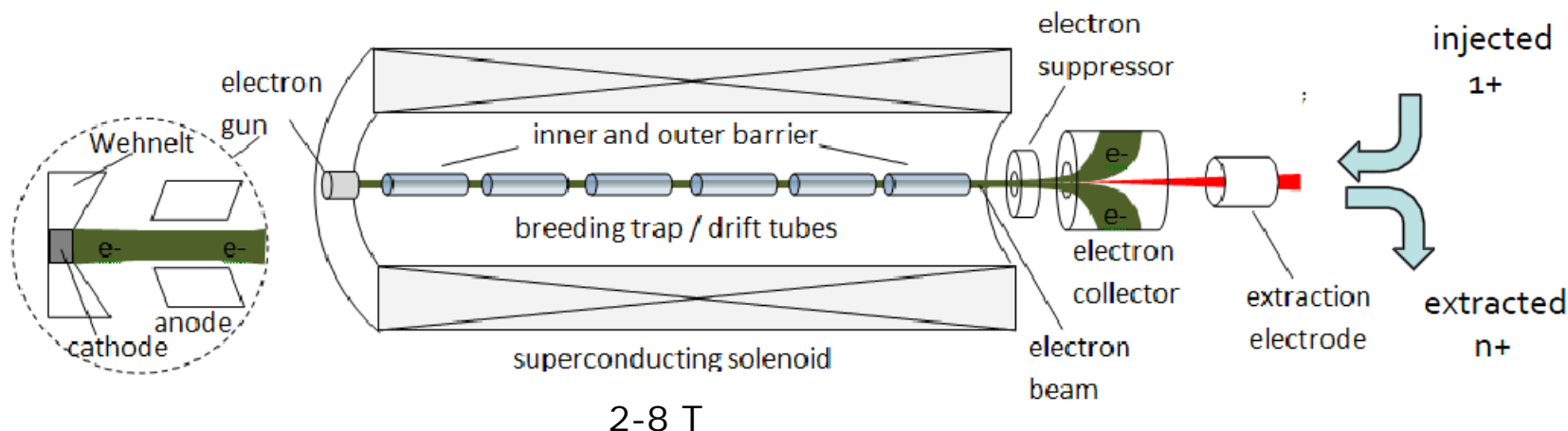
ECRIS CB Ion Capture

➤ Coulomb collision → thermalisation → diffusion → ionization → capture



EBIS Technology

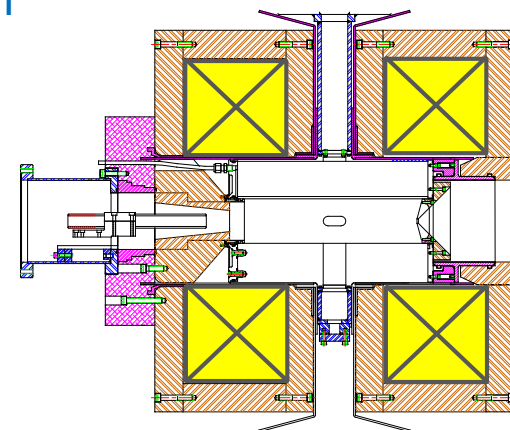
- Pulsed
- 1+ intensity limited to $\sim \text{nA}$ ($< 10^{10} \text{ pps}$)
- 1+N+ Efficiency $\sim 25\text{-}30\%$ / Very High Charge state
- Hot electron density $\sim 10^{13} - 10^{14} \text{ cm}^{-3}$
 - short total CB time $\sim 10 \text{ ms}$, even for highly charged ions
- Base vacuum $\sim 10^{-10} \text{ mbar}$
- Electrons created and dumped outside the trap
 - Low contamination induced : $10^2 - 10^3 / \text{s}$ per $\frac{M}{\Delta M} \sim 300$



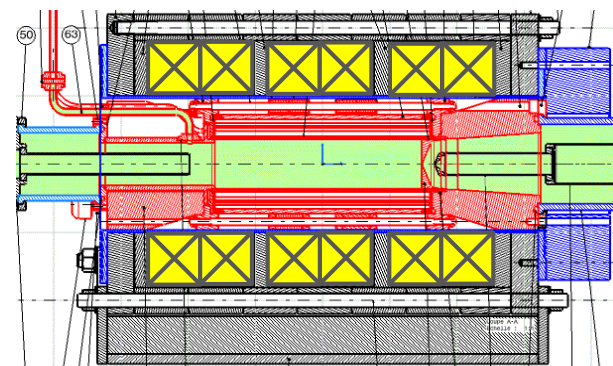
Source : F. Wenander CAS 2012

Today ECRIS CB technology

- Based on 20-30 years old 14 GHz ECRIS design
- CW or pulsed 1+ beam
up to $\sim 1\text{-}10\text{ }\mu\text{A}$ ($\sim 10^{13} - 10^{14}\text{ pps}$)
- CB time $\sim 1\text{-}10\text{ ms/charge}$
- 1+N+ Efficiency 1 charge state: $\sim 5\text{-}20\%$
- Max charge state:
 - $A/Q \sim 3$ up to $A=50$
 - $A/Q \sim 7$ up to $A=150$
- Vacuum $\sim 10^{-7} - 10^{-8}\text{ mbar}$ (non UHV)
 - Gas contamination
- The plasma intercepts the walls
 - condensable sputtering from stainless steel, copper, aluminum alloy...
 - ANL result: within $\frac{M}{\Delta M} \sim 300$, contamination $\sim 10^4\text{ pps}$



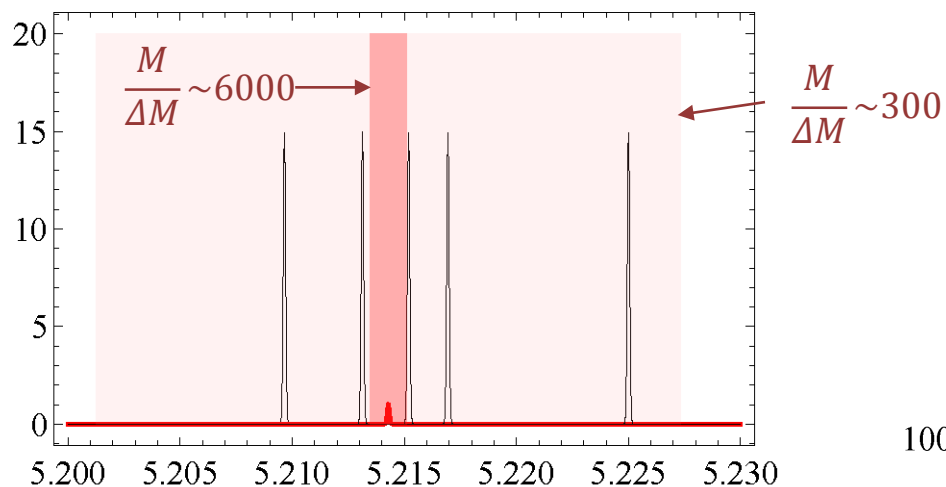
A-ECR (ANL)



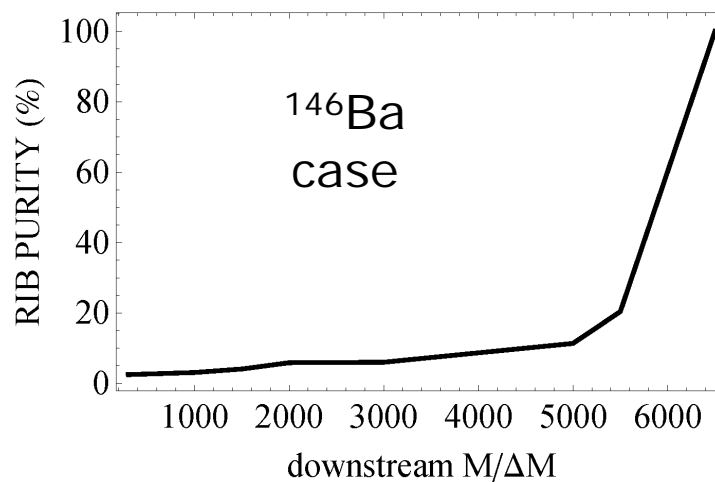
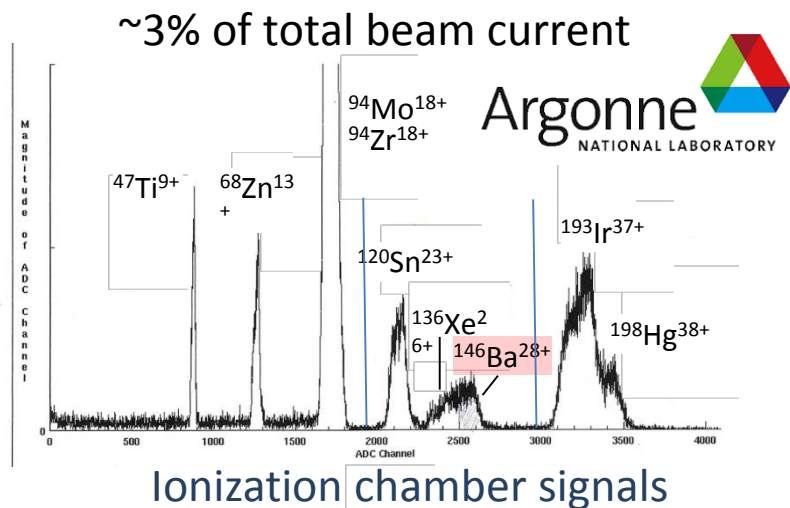
PHOENIX BOOSTER
(LPSC, GANIL, TRIUMF, SPES)

ANL Experience : ^{146}Ba run

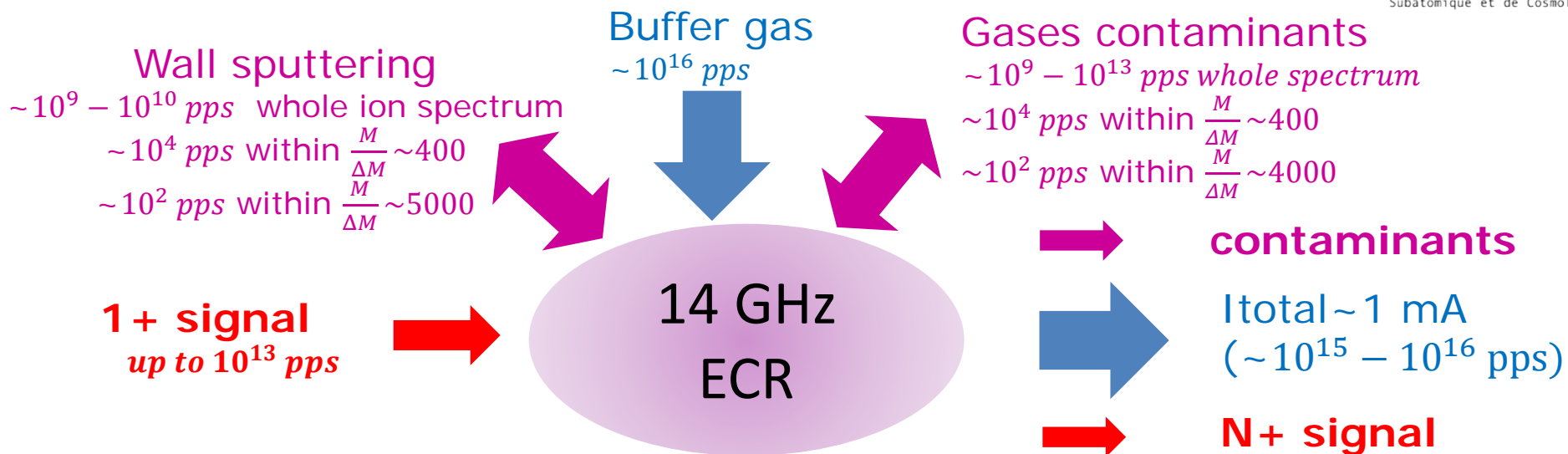
- 2.7% of RIB content in the beam
with $\frac{M}{\Delta M} \sim 300$



- 60% RIB would need $\frac{M}{\Delta M} \sim 6000$
- 60% RIB in $\frac{M}{\Delta M} \sim 300$ would need RIB intensity increased by 60



Orders of Magnitudes



- **Signal** to **noise** ratio is a key parameter for ECRIS CB at low RIB intensity:

Signal (pps)	10^2	10^3	10^4	10^5	10^6
For $\frac{M}{\Delta M} \sim 300$					
Signal/Noise	0.01	0.1	1	10	100
N+ RIB fraction	0.9%	9%	50%	91%	99%
For $\frac{M}{\Delta M} \sim 6000$					
Signal/Noise	1	10	100	1000	10000
N+ RIB fraction	50%	91%	99%	99.9%	99.99%

CARIBU (ANL) , TRIAC (TRIUMF)

Is it Game Over for ECR CB?

- Performances are based on 20 years old ion source designs
 - Not UHV, plastic O-rings, many materials facing plasma
 - Magnetic field and volume not optimized
- Ion Source know-how dramatically improved since 20 years



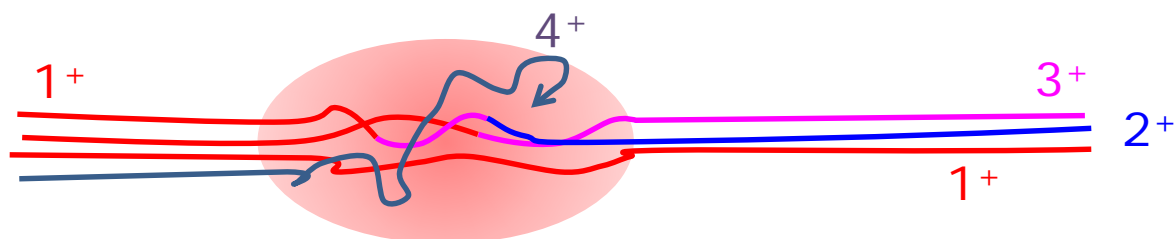
NO!

LET'S REVIEW WHAT CAN BE DONE

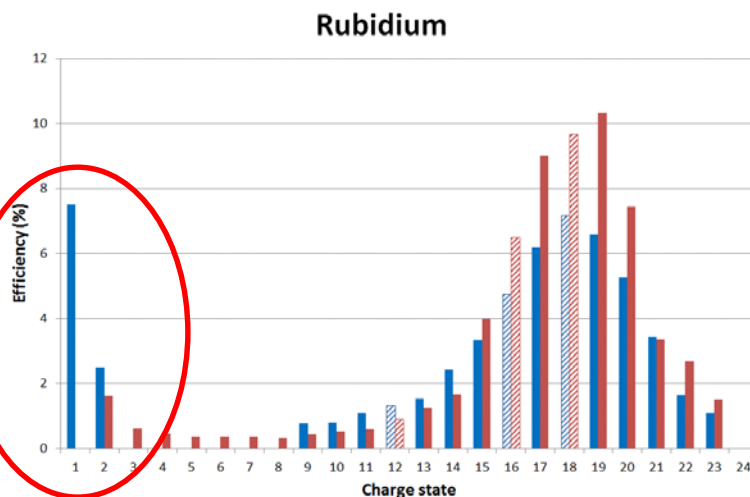
Improve the ion capture

➤ Optimize the capture with a longer (or denser) plasma

- Today, a part of the $1+$ beam is not captured, even some $2+$ and $3+$ are ionized on flight and not captured (10-20% lost)



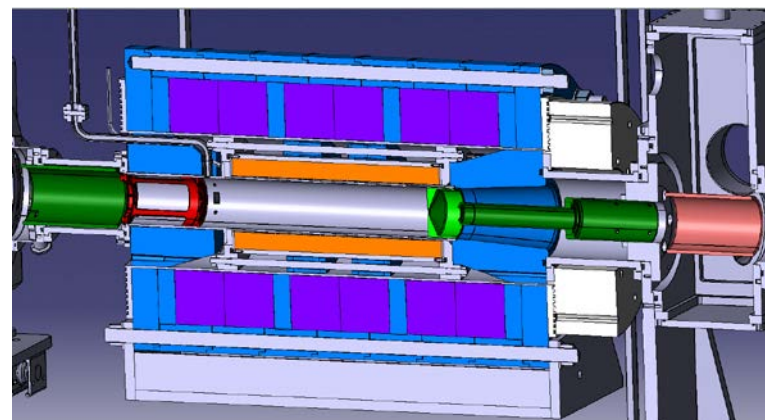
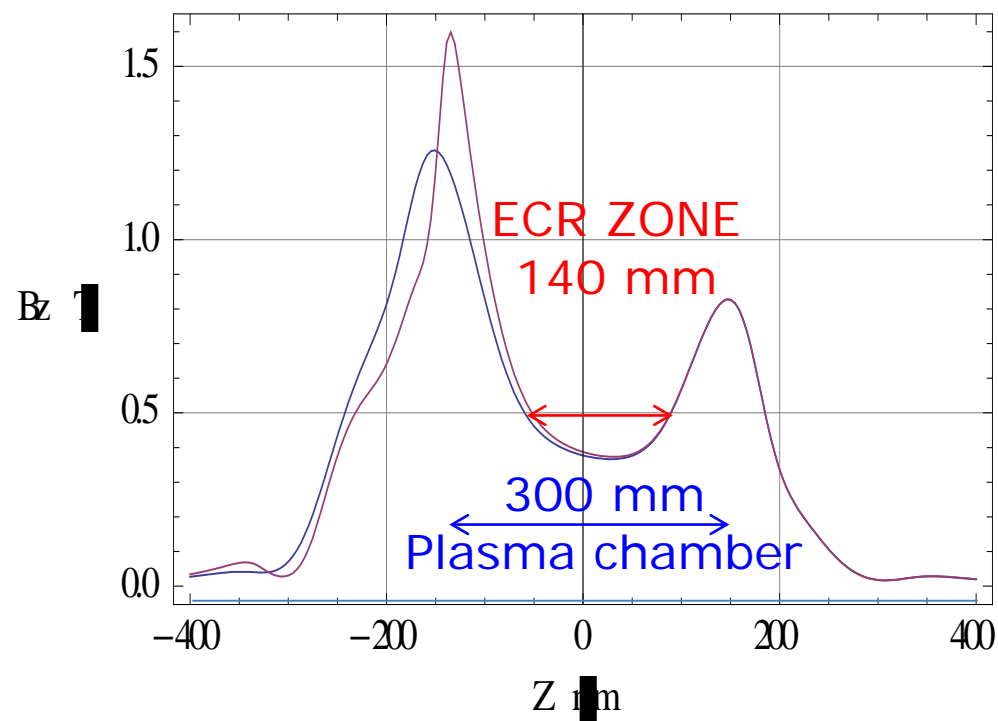
10-20%
Non-captured
ions



Improve the ion capture

➤ Indirect experimental confirmation with PHOENIX ECR CB

- The axial magnetic field profile maximizing the $1+N+$ efficiency is the one maximizing the ECR zone length



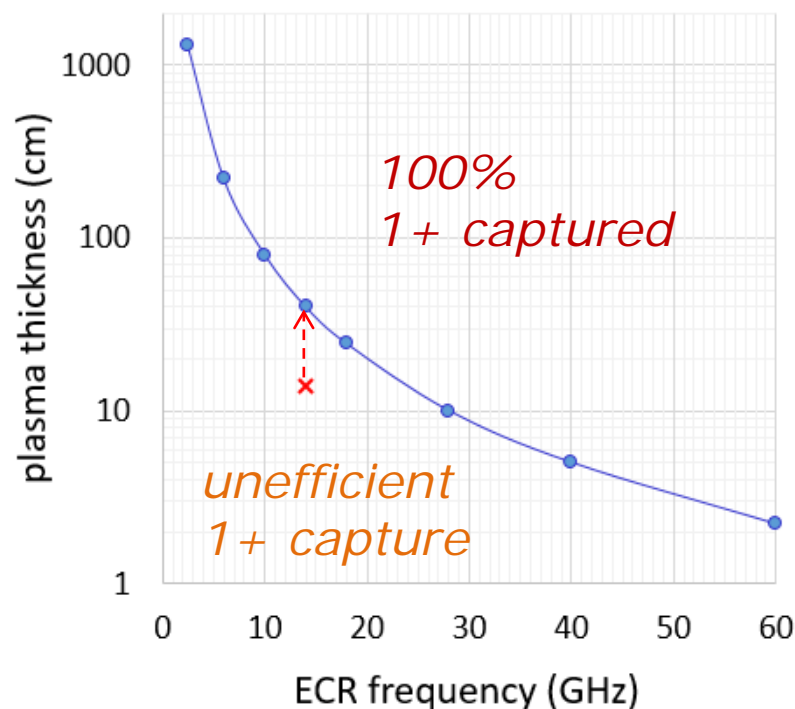
VENUS ECR zone length
is ~ 180 mm @18+28 GHz
For a 500 mm long plasma
chamber

Improve the ion capture

- Lengthening the ECR plasma of the booster at 14 GHz:
 - from 14 to 40 cm would grant a 99% $1+$ capture
- At higher frequency (eg: 18 GHz):
 - 25 cm plasma is necessary to capture all the $1+$

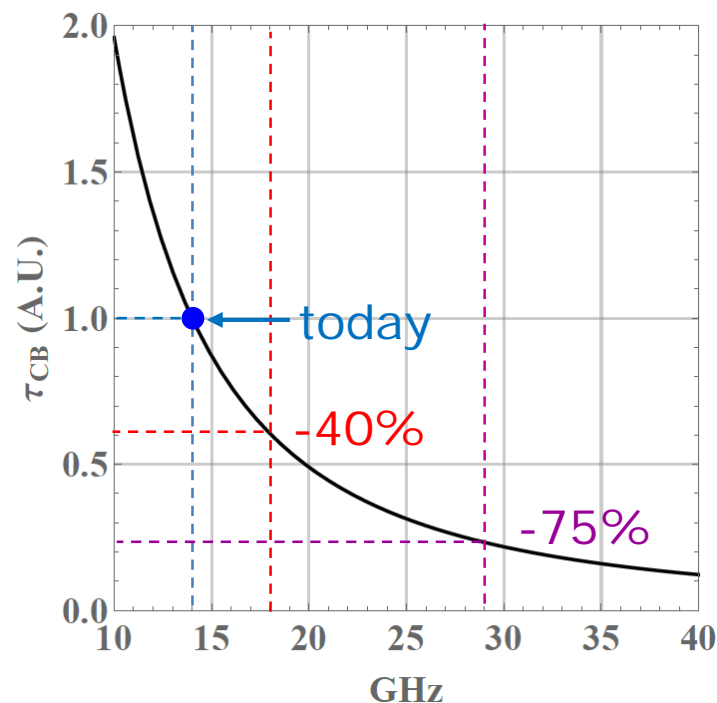
→ $1+N+$ Efficiency would increase up to +20%

Condition to get 99% of $1+$ ions captured



Reduce the CB time?

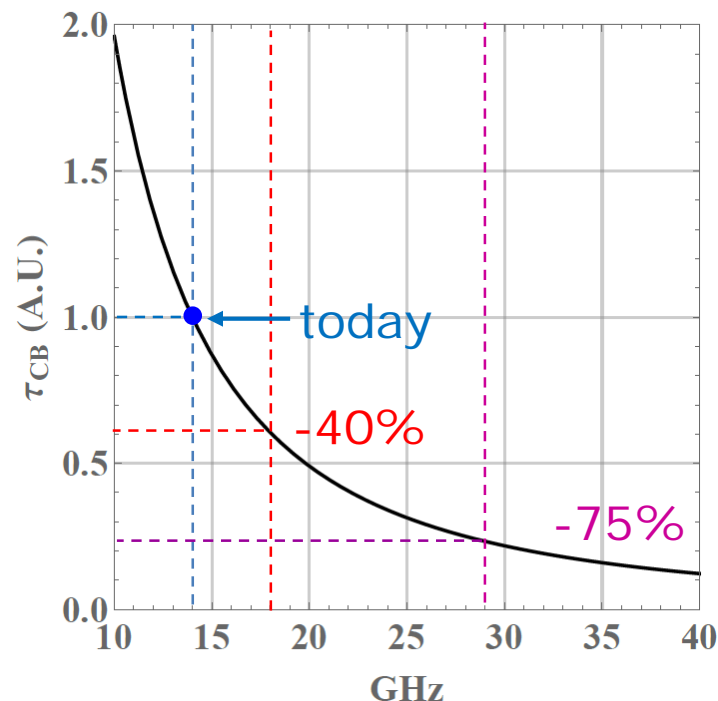
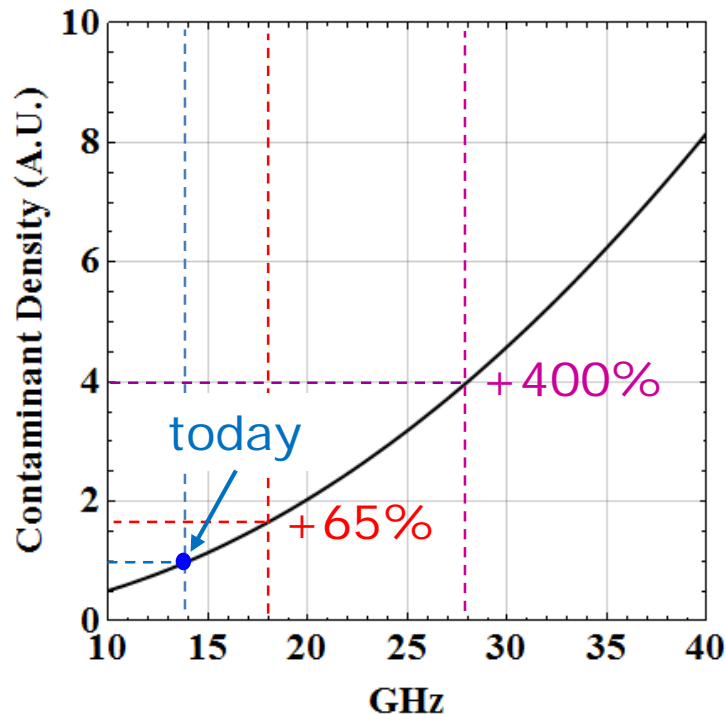
- ECR frequency scaling law : no limit so far up to 28 GHz operation
- Plasma density : $n_p \leq \frac{4\pi^2 m_e \epsilon_0}{e^2} f_{ECR}^2$
- Charge Breeding Time: $\tau_{CB} \propto \frac{1}{n_p} \propto f_{ECR}^{-2}$
 - Today, standard ECR CB are operated at $f_{ECR} = 14$ GHz
 - An 18 GHz ECR CB would reduce τ_{CB} by -40%
 - A 28 GHz ECR CB would reduce τ_{CB} by -75%
 - With respect to 14GHz operation



GREAT PROSPECT, **BUT** ...

Reduce the CB time?

- A « catch 22 » situation as contaminant density follows: $n_e \propto f_{ECR}^2$



CB time reduction is opposed to background reduction
 CB reduction time would work with
 a very high mass separator downstream ($\frac{M}{\Delta M} \sim 6000$)
 Background reduction is a key parameter

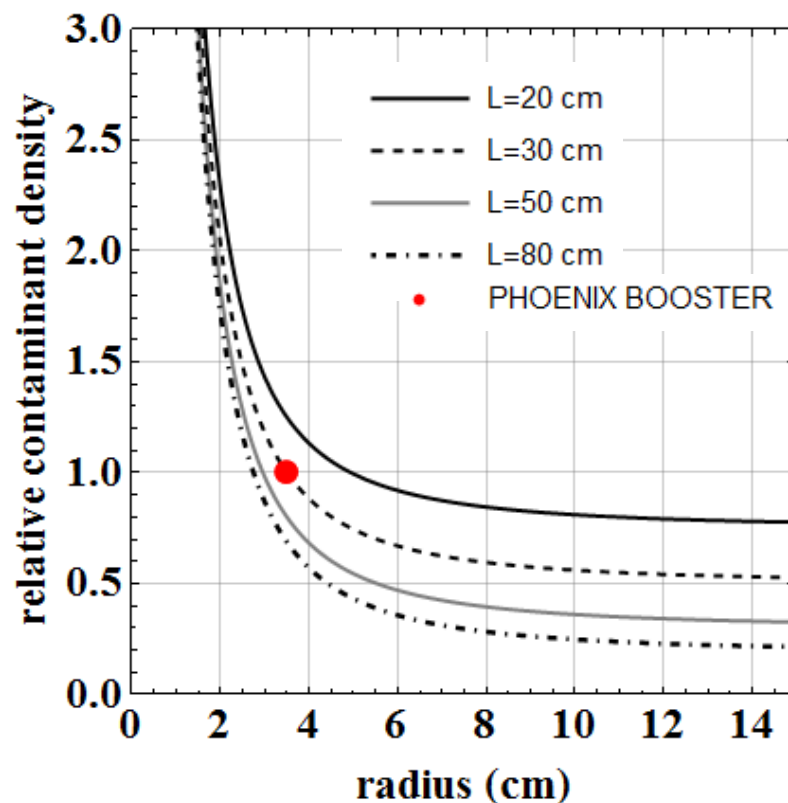
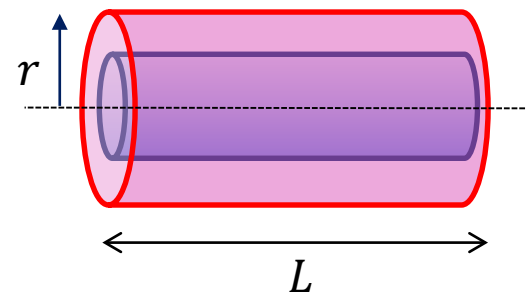
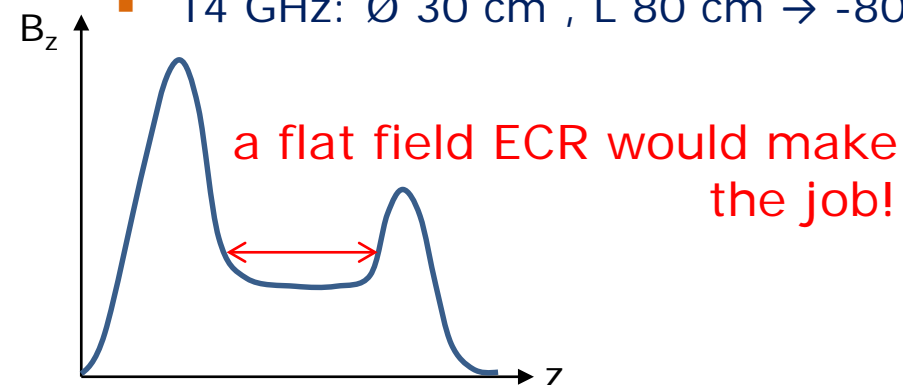
Reduce wall contamination

➤ Geometrical background reduction :

- Contaminant flux from wall is $\propto S = 2\pi rL + 2\pi r^2$
- Plasma volume is $\propto V = \pi r^2 L$
- Contaminant density $C \propto \frac{S}{V} = \frac{2}{r} + \frac{2}{L}$
- Increasing plasma chamber radius r and length L reduces the contaminant density

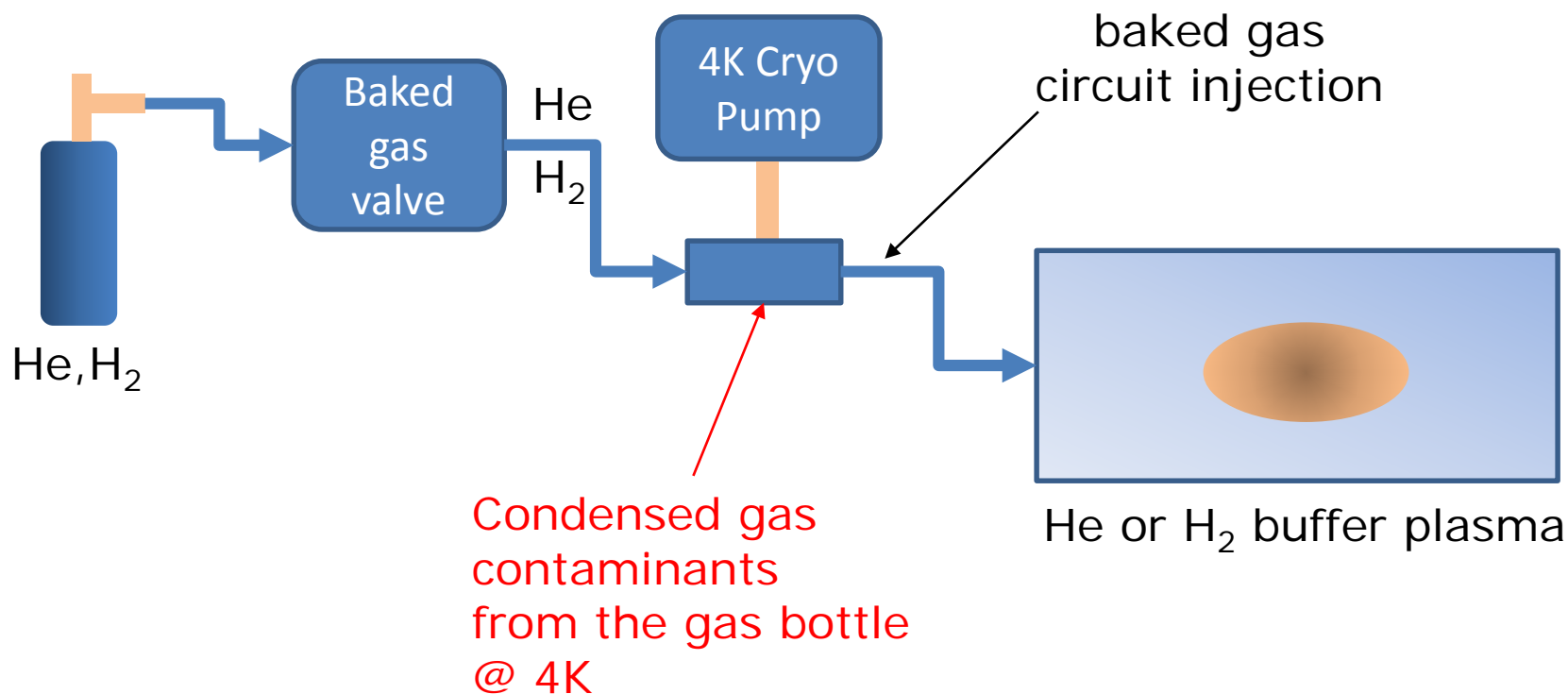
14 GHz: Ø 16 cm , L 50 cm → -60%

14 GHz: Ø 30 cm , L 80 cm → -80%



Reduce gas contamination

- Follow ANL steps to get rid of gas contamination
- Use He or H₂ as buffer gas

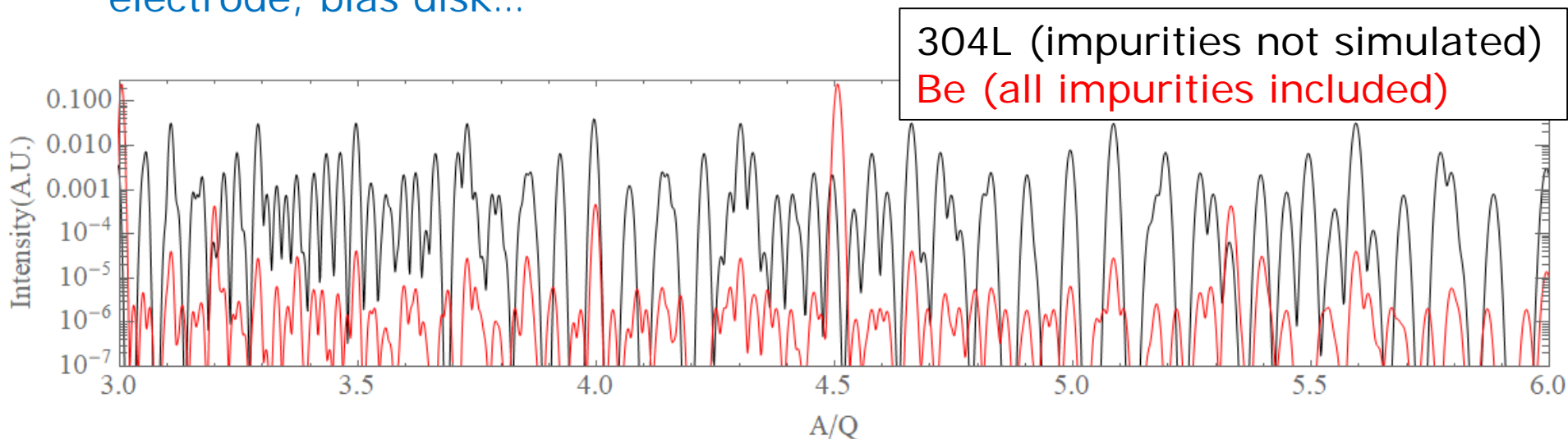
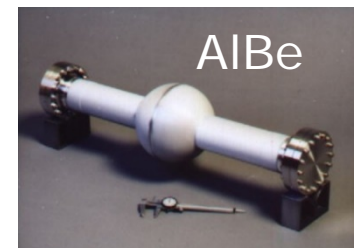


Reduce gas contamination

- Make a fully UHV Bakeable ECRIS Booster
 - Get rid of all the plastic O-rings
- Make a fully UHV Bakeable LEBT
 - With differential pumping close to the ECR CB
 - Get a $10^{-9} - 10^{-10}$ *mbar* base pressure
 - Have gas contaminant reduced by a factor 100

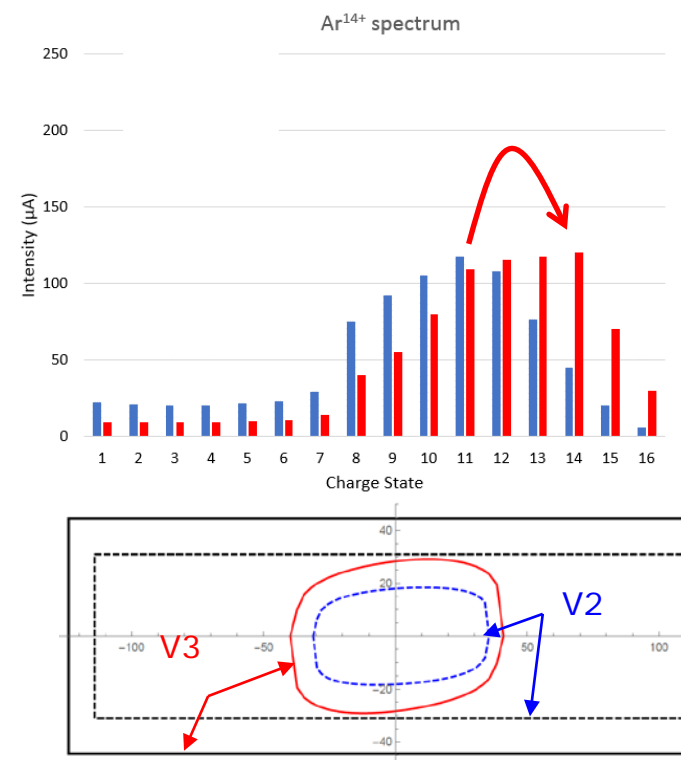
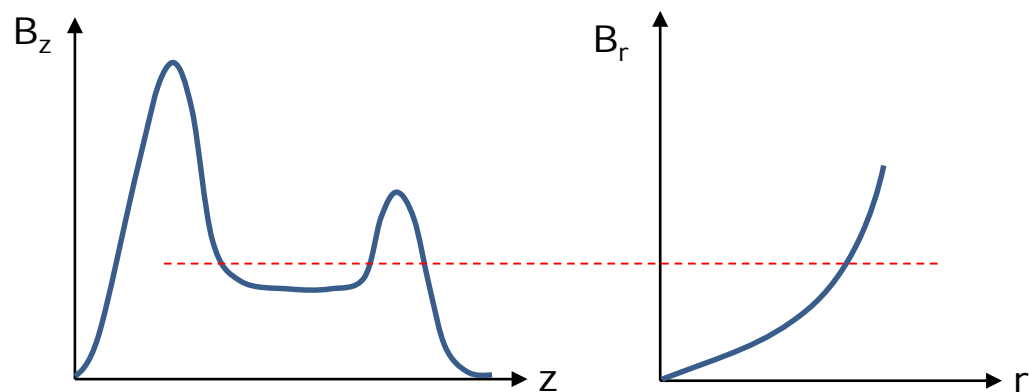
Minimize the contaminant species

- Go further with the R&D performed by ANL, TRIUMF, SPES, GANIL
 - Extend the M/Q spectrum areas with low background
- Banish complicated alloys to make the plasma chamber AND the Surrounding vacuum chambers
 - Select a pure material without isotopes, as light as possible:
 - ^4Be (melts 1287°C); ^{27}Al (melts 660°C) AlBe (melts 644°C);
 ^{55}Mn ; ^{59}Co ; ^{93}Nb ; ^{181}Ta ; ^{197}Au
 - The lighter the mass, the better
- And have everything made with this material: waveguide, plasma electrode, bias disk...



Increase the N+ ion charge state

- Optimize the magnetic confinement using up to date know-how
- Larger plasma chamber radius
 - Shown with PHOENIX V2→V3 upgrade (SPIRAL2)
- With an optimized ECR CB:
 - Xe^{42+} ($A/Q \sim 3$; $A=132$)
 - U^{42+} ($A/Q \sim 6$; $A=238$)



Summary

➤ What can be improved in ECR charge breeders?

- Capture efficiency => +20% $1+N^+$ efficiency
- Higher Charge states (U^{42+} , Xe^{42+}) with better magnetic confinement
- Gas contaminant can be reduced by a factor 100 at least
- Condensable contaminant density can be geometrically reduced by -80%
- Condensable peak distribution can be favorably concentrated on a few peaks => 1/100 to 1/1000 reduction possible
- charge breeding time can be reduced by -75% at 28 GHz ECR frequency provided the RIB facility gets a very high resolution spectrometer
($\frac{M}{\Delta M} \sim 6000$)

➤ Is it worth continuing R&D? YES!

Upgraded Charge Breeder for EURISOL

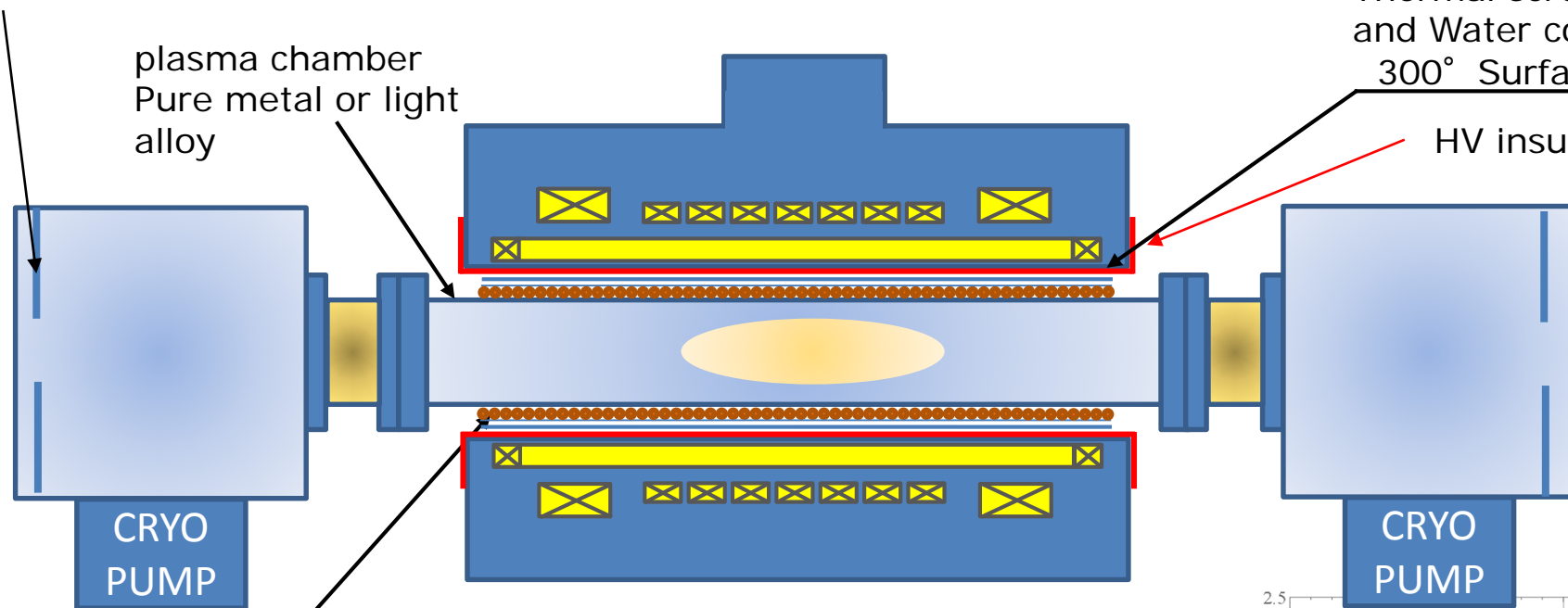
Flat Field ECR CB @ 14-18 GHz, NbTi@4 K

differential
pumping

plasma chamber
Pure metal or light
alloy

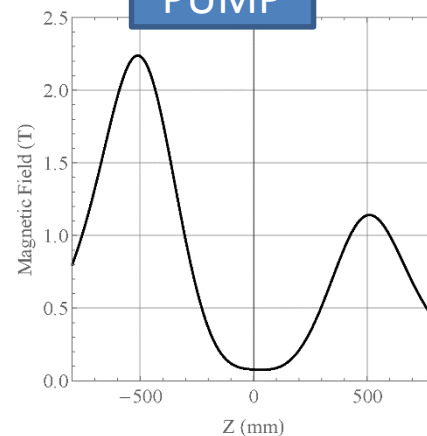
Thermal screen
and Water cooled
300° Surface

HV insulator



Heater wire to bake
The plasma chamber
Online up to 400° C

Plasma chamber:
Ø200 mm
L ~ 1000 mm
ECR Zone ~ 500 mm



EURISOL

ECRIS18 WORKSHOP CO₂ FOOTPRINT

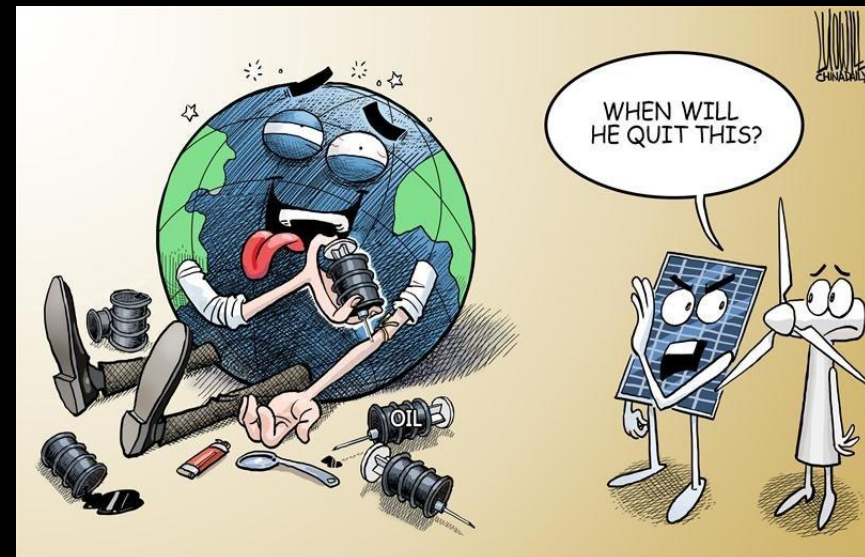
city	round trip	#	kg CO ₂
Argonne	1130,208	1	1130
Beijing	934,276	3	2803
Berkeley	1637,24	3	4912
Bhat	1114,836	1	1115
Busan	1307,596	2	2615
Caen	383,324	4	1533
College station	1626,016	1	1626
Debrecen	366	2	732
Dubna	600,728	3	1802
East Lansing	1098,732	2	2197
Darmstadt	404,552	2	809
Geneve	672,952	2	1346
Groningen	445,788	1	446
Jyvaskyla	664,168	3	1993
Kyoto	1527,196	1	1527
Lanzhou	1221,708	7	8552
Grenoble	319,152	3	957
Legnaro	268,888	2	538
Nizhnyi	817,4	4	3270
Saclay	383,324	2	767
Lund	462,38	1	462
Nishina	1302,716	1	1303
Xi'an	1164,368	1	1164
		52	43599
	per capita		838

43 TONS
of CO₂

20 TONS
Kerozene

0.3 TWh

13000 years
Of 1 slave
Work



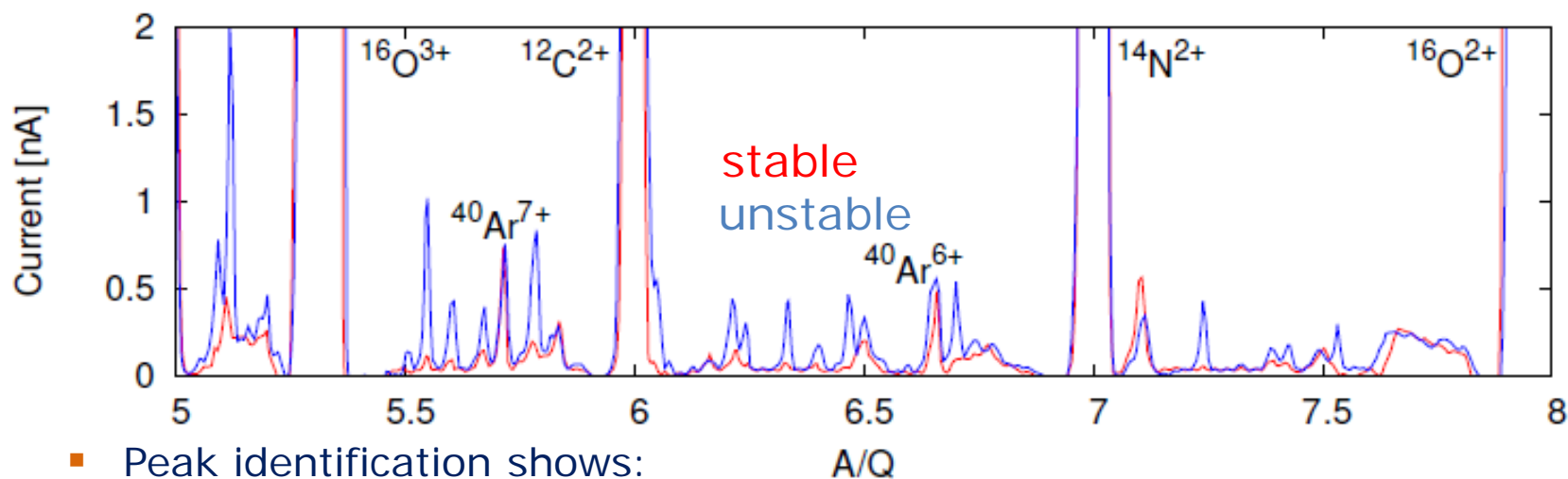
**THANK YOU FOR YOUR
ATTENTION**

Plasma stability and background level

➤ Plasma kinetic instabilities transiently generate a huge plasma potential

- $V_p \sim 1$ kV
- Strong sputtering from the wall

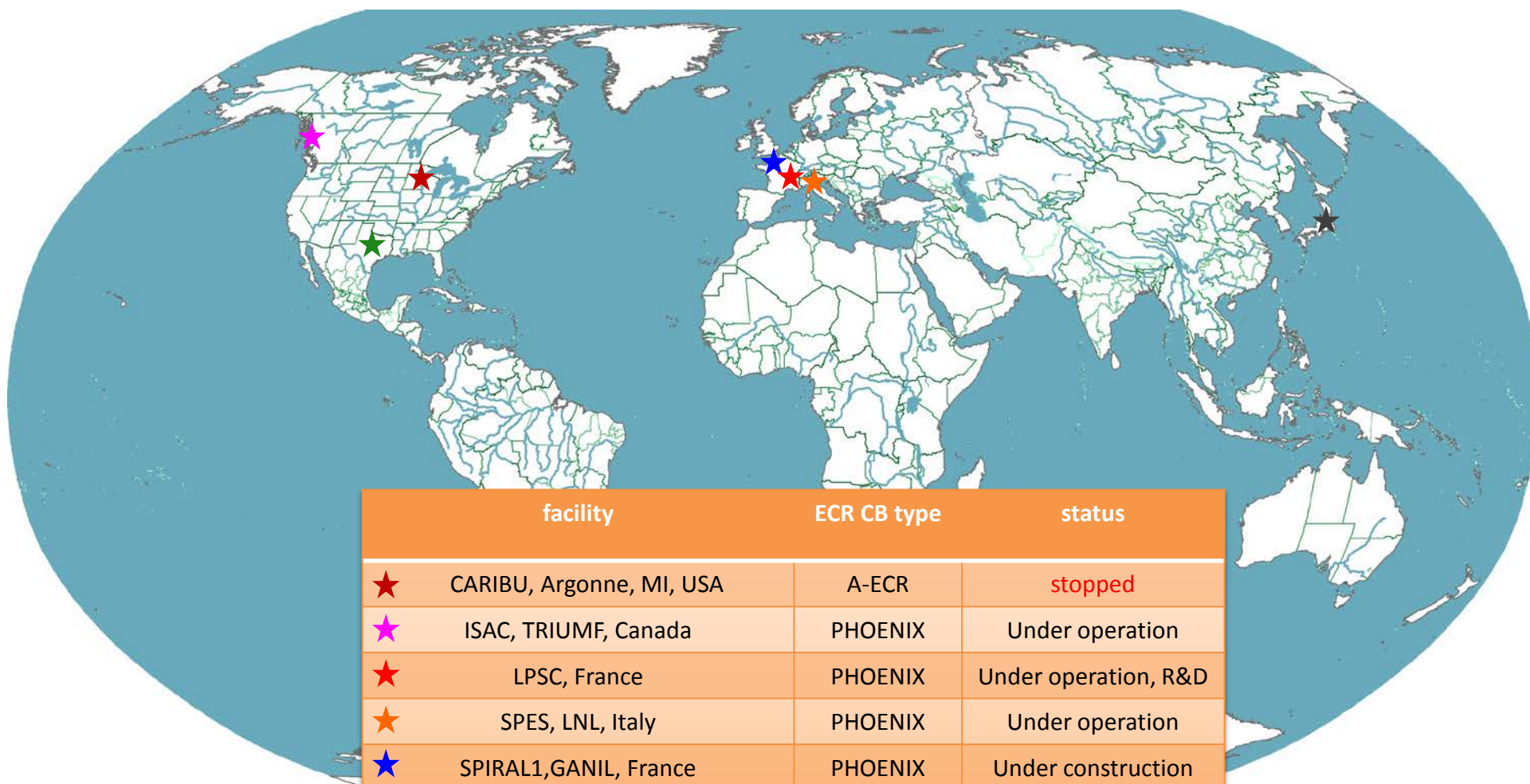
Joint study with JYFL & IAP RAS



- Peak identification shows:
 - stainless steel plasma chamber composition: Fe, Cr, Mo, Ni, Al, Zn, Cu, Mn
 - Electrodes composition (Al alloy 2017): Al, Cu, Mn, Zn
 - Release of previous condensed 1+ beam (Cs,Rb,K)

Prospect: Make sure next ECR CBs operate with a steady plasma

ECR Charge Breeders in the World



facility	ECR CB type	status
★ CARIBU, Argonne, MI, USA	A-ECR	stopped
★ ISAC, TRIUMF, Canada	PHOENIX	Under operation
★ LPSC, France	PHOENIX	Under operation, R&D
★ SPES, LNL, Italy	PHOENIX	Under operation
★ SPIRAL1, GANIL, France	PHOENIX	Under construction
★ Texas A&M, College station, TX, USA	A-ECR	Under operation
★ TRIAC, KEK- JAERI, Japan	KEK-CB	Facility closed